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## **Supplementary Information**

## Design principle for p-type oxide gate layer on AlGaN/GaN toward

## normally-off HEMTs: Li-doped NiO as model +

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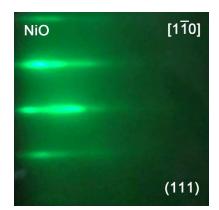


Fig. S1. RHEED pattern of NiO thin films on Al<sub>2</sub>O<sub>3</sub> substrates.

Fig. S1 shows the RHEED pattern of NiO thin films on  $Al_2O_3$  substrates. The above similar RHEED pattern with NiO on GaN indicates the similar epitaxial crystal structure of NiO thin films on GaN and  $Al_2O_3$  substrates.

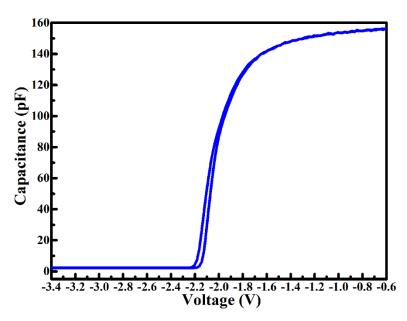


Fig. S2. C-V characteristic of Pt/Ni\_{0.75}Li\_{0.25}O/AlGaN/GaN/Si heterostructure.

Fig. S2 displays C-V curve of Pt/Ni $_{0.75}$ Li $_{0.25}$ O/AlGaN/GaN/Si heterostructure. The small voltage window indicates good interfacial state at Ni $_{0.75}$ Li $_{0.25}$ O/AlGaN interface.

E <sub>C</sub> <sup>NLO</sup>		
$E_g^{\text{NLO}}$ =3.65 eV	E <sub>C</sub> AGN	$\Delta E_{C3}$ =0.33 eV $E_C^{GN}$
	$E_g^{\text{AGN}}$ =3.84 eV	<i>E</i> <sup>GN</sup> <sub>g</sub> =3.84 eV
Ni <sub>0.75</sub> Li <sub>0.25</sub> O		1.95 ev
$E_V^{\text{NLO}} \Delta E_V = 1.56 \text{ eV}$	Al <sub>0.22</sub> Ga <sub>0.78</sub> N	GaN
	$E_V^{AGN}$	$E_V^{ m GN}$

Fig. S3. Band alignment of  $Ni_{0.25}Li_{0.25}O/AI_{0.22}Ga_{0.78}N/GaN$  heterostructure.

Fig. S3 shows the band alignment of Ni<sub>0.75</sub>Li<sub>0.25</sub>O/Al<sub>0.22</sub>Ga<sub>0.78</sub>N/GaN heterostructure. The ratios of conduction band discontinuities to valence band discontinuities are 75:25 for AlGaN/GaN interface in the reported results.<sup>36</sup> Thus the valance band offset ( $\Delta E_{C3}$ ) value at Al<sub>0.22</sub>Ga<sub>0.78</sub>N/GaN interface is calculated to be 0.33 eV. Therefore, intrinsic  $E_C^{GaN} - E_V^p$  value is determined to be 1.95 eV calculated by  $E_g^{AGN} - \Delta E_V - \Delta E_{C3}$ .